

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kiyoshi Arita

Serial No.: TBD Art Unit: TBD

Filing Date: Herewith

Title: METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE, PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING METHOD

Docket No.: 36280

INFORMATION DISCLOSURE STATEMENT

Mail Stop PATENT APPLICATION
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with Rule 56, applicant is aware of the publications listed in the enclosed copy of Patent Office Form 1449. A copy of each of the publications is enclosed herewith.

Respectfully submitted,

PEARNE & GORDON LLP

By:


Jeffrey J. Sopko, Reg. No. 27676

1801 East 9th Street
Suite 1200
Cleveland, Ohio 44114-3108
(216) 579-1700

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INFORMATION DISCLOSURE CITATION
BY APPLICANT
(USE SEVERAL SHEETS IF NECESSARY)

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U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Date	Name	Class	Subclass	Filing Date
	A						
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FOREIGN PATENT DOCUMENTS

		Document No.	Date	Country	Class	Subclass	Translation
	M	2002-93752	3/2002	JP			Cited in Specification
	N						
	P						
	Q						

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

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